

Application No.: 10/772,510
 Filed: February 5, 2004
 Amendment dated: January 30, 2008
 Reply to Office Action of October 30, 2007

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re:	Detlef Michelsson	Confirmation No:	5672
Serial No:	10/772,510	Art Unit:	2624
Filed:	February 5, 2004	Examiner:	Fujita, Katrina R.
For:	Method and Apparatus for Examining Semiconductor Wafers in a Context of DIF/SAW Design		
Customer No.:	29127		
Attorney Docket No.	21295.74 (H5742US)		

AMENDMENT AFTER FINAL ACTION

Fax: 571-273-8300

Mail Stop AF
 Commissioner for Patents
 P.O. Box 1450
 Alexandria, VA 22313-1450

OK to enter
 6/21/08

Sir:

In response to the pending final Office Action, mailed October 30, 2007 (Paper No. 20071025), please amend the above-captioned application as follows:

Amendments to the Claims are reflected in the listing of claims in the Amendments to the Claims section.

Reconsideration is requested in view of the remarks set forth in Remarks/Arguments section.